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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE  
(Case No. 207.010-US)

In the Application of: LUTZ ET AL.

Serial No: 10/698,268

Filed: OCTOBER 31, 2003

Title: ANTI-STICKTION TECHNIQUE FOR THIN FILM  
AND WAFER-BONDED ENCAPSULATED  
MICROELECTROMECHANICAL SYSTEMS

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

)  
Group  
Art Unit: 2814  
)  
Before  
Examiner  
)

I hereby certify that this correspondence  
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Michiko Saito  
(person signing this certificate)

Michiko Saito  
Signature

**SECOND INFORMATION DISCLOSURE STATEMENT**

Dear Sir:

Submitted herewith is one (1) sheets of a modified Form PTO-1449. A copy of each document cited on the attached Form PTO-1449 is also submitted.

It is respectfully requested that the Examiner make his/her consideration of these documents formally of record with the initial Office Action.

Respectfully submitted,

Neil A. Steinberg  
Reg. No. 34,735  
650-968-8079

Date: June 10, 2004



Sheet 1 of 1

PTO-1449 (Modified) U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE  INFORMATION DISCLOSURE STATEMENT BY APPLICANT	ATTY. DOCKET NO. 207.010-US	SERIAL NUMBER 10/698,258
	APPLICANT(S) Lutz et al.	
	FILING DATE October 31, 2003	GROUP ART UNIT 2814

## U.S. PATENT DOCUMENTS

EXAMINER INITIALS	DOCUMENT NUMBER	DATE	NAME	CLAS S	SUB CLAS S	FILING DATE
	4,849,071	7/1989	Evans et al.			
	4,945,769	8/1990	Sidner et al.			
	5,445,991	8/1995	Lee			
	5,470,797	11/1995	Mastrangelo			
	5,616,514	4/1997	Muchow et al.			
	6,521,508	2/2003	Cheong et al.			

## FOREIGN PATENT DOCUMENTS

EXAMINER INITIALS	DOCUMENT NUMBER	DATE	COUNTRY	CLAS S	SUB CLAS S	TRANSLATION YES/NO

## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

"Chemical Vapor Deposition of Fluoroalkylsilane Monolayer Films for Adhesion Control in Microelectromechanical Systems", Mayer et al., J. Vac. Sci. Technol. B 18(5), Sept/Oct 2000, pp.2433-2440

EXAMINER	DATE CONSIDERED

EXAMINER: Initial citation if reference was considered. Draw line through citation if not in conformance to MPEP 609 and not considered. Include copy of this form with next communication to applicant.